



Micromachines for Dielectrophoresis, Volume II

Guest Editor:

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Deadline for manuscript
submissions:

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Message from the Guest Editor

Dielectrophoresis (DEP) remains an effective technique for the label-free identification and manipulation of targeted particles. Applications are numerous, ranging from clinical diagnostics and therapeutics to advanced manufacturing. This Special Issue emphasizes novel techniques and processes for the fabrication of the next generation of devices that will further widen the range of applications of DEP. These innovations include new materials and geometries, volumetric three-dimensional (3D) structures, cost-reducing approaches, large-scale manufacturing, and disposable devices. Submissions that assess the effect of process parameters on the performance of DEP devices are particularly encouraged. Submissions integrating modeling and experimentation are preferred.





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Message from the Editor-in-Chief

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